

**Notice of References Cited**

Application/Control No.

09/921,786

Applicant(s)/Patent Under  
Reexamination  
DREVILLON ET AL.

Examiner

Carlos Ortiz-Rodriguez

Art Unit

2125

Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-5,223,356 ✓	06-1993	Kumar et al.	430/1
	C	US-5,494,697 ✓	02-1996	Blayo et al.	427/10
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	E	US-6,504,608 ✓	01-2003	Hallmeyer et al.	356/369
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	L	US-			
	M	US-			

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	N	EP0653621A1 ✓	05-1995	DE FR GB	Blayo, Nadine	GO1N 21/21
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**NON-PATENT DOCUMENTS**

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	U	Kildemo et al., "Real time control of the growth of silicon alloy multilayers by multiwavelength ellipsometry"; Thin Solid Films, Dec. 1996; Vol. 290-291; pages 46-50. ✓			
	V	M. Kildemo et al., "A direct robust feedback method for growth control of optical coatings by multiwavelength ellipsometry"; Thin Solid Films, Dec. 1998; Vol. 313-314; pages 484-489. ✓			
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.